



162162



G00002

Abstract

A MEMS Accelerometer

A MEMS accelerometer employs one or more elements of piezoelectric material which are deformed when the accelerometer is subjected to acceleration, and generate a measurable electric signal. In a preferred form, the accelerometer includes a base member 2, two parallel beams 3, 5 and a proof mass member 7. The proof mass member 7 is supported by the beams 3, 5 which, if the proof mass member 7 is displaced from a rest position, urge it back towards that position. The beams 3, 5 include a semiconductor substrate, and on it a bottom electrode layer, piezoelectric layer and top electrode layer.

[Fig. 1(a)]